



Atty. Dkt. No. 023312-0109

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Takashi NAGASE et. al.
Title: METHOD OF
MANUFACTURING NANO-GAP
ELECTRODE
Appl. No.: 10/662,886
Filing Date: 09/16/2003
Examiner: Unassigned
Art Unit: Unassigned

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.56

Commissioner for Patents
PO Box 1450
Alexandria, Virginia 22313-1450

Sir:

Submitted herewith on Form PTO/SB/08 is a listing of documents known to Applicants in order to comply with Applicants' duty of disclosure pursuant to 37 CFR §1.56. A copy of each listed document is being submitted to comply with the provisions of 37 CFR §1.97 and §1.98.

The submission of any document herewith, which is not a statutory bar, is not intended as an admission that such document constitutes prior art against the claims of the present application or that such document is considered material to patentability as defined in 37 CFR §1.56(b). Applicants do not waive any rights to take any action which would be appropriate to antedate or otherwise remove as a competent reference any document which is determined to be a *prima facie* art reference against the claims of the present application.

TIMING OF THE DISCLOSURE

The listed documents are being submitted in compliance with 37 CFR §1.97(b), before the mailing date of the first Office Action on the merits.

RELEVANCE OF EACH DOCUMENT

All of the documents are in English.

Applicants respectfully request that any listed document be considered by the Examiner and be made of record in the present application and that an initialed copy of Form PTO/SB/08 be returned in accordance with MPEP §609.

The Commissioner is hereby authorized to charge any additional fees which may be required regarding this application under 37 CFR §§ 1.16-1.17, or credit any overpayment, to Deposit Account No. 19-0741. Should no proper payment be enclosed herewith, as by a check being in the wrong amount, unsigned, post-dated, otherwise improper or informal or even entirely missing, the Commissioner is authorized to charge the unpaid amount to Deposit Account No. 19-0741.

Respectfully submitted,

Date

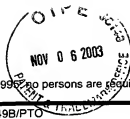
11/6/03

By



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MODIFIED PTO/SB/08 (08-00)
Approved for use through 10/31/2002. OMB 0551-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT Date Submitted: 11/6/03 (use as many sheets as necessary)			Complete if Known Application Number: 10/662,886 Filing Date: 09/16/2003 First Named Inventor: Takashi NAGASE Group Art Unit: Unassigned Examiner Name: Unassigned Attorney Docket Number: 023312-0109		
Sheet	1	of	1		

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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FOREIGN PATENT DOCUMENTS								
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NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.		T ⁶
	A4	R.L. Kubena, et al, A Low Magnification Focused Ion Beam System with 8 nm spot size", J. Vac. Sci. Technol. B9, 3079-3083 (1991)		Y
	A5	S. Matsui, et al, High Resolution Focused Ion Beam Lithography, J. Vac. Sci. Technol. B9, 2622-2632 (1991)		Y
	A6	M.A. Reed, Molecular-Scale Electronics, Proc. IEEE, 87, 652-658 (1999)		Y
	A7	A. Aviram, et al, Molecular Electronics II, New York Academy of Sciences, New York (2002) – Table of Contents		Y
	A8	Y. Wada, et al., Prospects and Problems of Single Molecule Information Devices, Jpn. J. Appl. Phys. Part 1, 39, 3835-3849 (2000)		Y

Examiner Signature	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language translation is attached.

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